Abstracts

High-Frequency On-Wafer Testing with Freely Positionable Silicon-on-Sapphire Photoconductive Probes

T. Pfeifer, H.-M. Heiliger, E.S. von Kamienski, H.G. Roskos and H. Kurz. "High-Frequency On-Wafer Testing with Freely Positionable Silicon-on-Sapphire Photoconductive Probes." 1995 MTT-S International Microwave Symposium Digest 95.3 (1995 Vol. III [MWSYM]): 1053-1056.

We describe the characterization of external photoconductive probes as both generators and detectors of picosecond electric transients. The probes are manufactured on transparent silicon-on-sapphire substrates and are suited for on-wafer testing in integrated circuits. We characterize the freely positionable probes concerning linearity, sensitivity, time resolution and invasiveness.

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